# Meni Kabla

Derech Hatachana 23/5 Rosh Pinna 12000

**Mobile:** 052-4290986 **e-mail:** menika@rafael.co.il

## ACADEMIC DEGREES

BSc (2000, Chemical engineering, Technion– Israel Institute of Technology)
MSc (2007, Chemical engineering, Technion – Israel Institute of Technology)
Ph.D (2016, Mechanical engineering, Technion – Israel Institute of Technology)

## PROFESSIONAL EXPERIENCE

**2011 – Today, Section head, Rafael** – Head of a development and fabrication team, composed from technicians and process engineers for the fabrication and development of MEMS devices.

**2007 – 2011, process engineering head, Rafael** – Head of process engineers group. Responsibility for process development and optimization, from mask layout and process design, lithography, dry and wet etch, thin film deposition and packaging.

**2002 – 2007, Process engineer, Rafael** – establishment of infrastructure and process development for the deposition of piezoelectric PZT thin films and integration these films into MEMS devices as actuators. Process development for vacuum sealing of MEMS devices, including outgassing profiling and getter activation.

2**001 – 2002, Finishing department head, Vishay Vitramon** – responsibility for electrical characterization and packaging of ceramic chip capacitors, including process engineering, operation and maintenance.

**1999 – 2001, Process engineer, Vishay Vitramon** – process optimization for ball milling of silver and ceramic pastes and buildup of thick film multi layer ceramic chip capacitors.

## PUBLICATIONS

Kabla M., Shilo D. (2016) Characterization of NiTi superelastic properties by Nano Dynamic Modulus Analysis and Nanoindentation, Functional Materials Letters (submitted)

Kabla M., Ben-David, E. Shilo D. (2015) A novel shape memory alloy micro actuator for large in-plane strokes and forces, Smart materials and structures (Accepted for publication)

Thomasová M., Sedlák P., Seiner H., Janovská M., Kabla M., Shilo D., Landa M. (2015) Young's moduli of sputter-deposited NiTi films determined by resonant ultrasound spectroscopy: Austenite, R-phase, and martensite ,Scripta Materialia 101:1-106.

Frost M., Kruisova A., Shanel A., Sedlak P., Landa M., Hausild P., Kabla M., Shilo D. (2015) Characterization of superelastic NiTi alloys by nanoindentation: experiments and simulations. Acta Pisica Polonica, Accepted for publication

Kabla M., Seiner H., Musilova M., Landa M., Shilo D. (2014) The relationships between sputter deposition conditions, grain size, and phase transformation temperatures in NiTi thin films, Acta Mater. 70:79–91.

## CONFERENCES

### Plenary, keynote or invited talks

Deposition and Characterization of NiTi Thin Films, Tel-Aviv University, Oct. 2012, ICME2012, plenary.
Deposition and Characterization of NiTi Thin Films on Full Wafer, SMST - Prague, Czech Republic, May. 2013, plenary.

Characterization of NiTi alloys by instrumented nanoindentation: experiments and simulations, SMST 2015,Oxfordshire, United Kingdom, May 2015, plenary.